1 9 2002 by certify that this correspondence is being deposited with the United States

CERTIFICATE OF MAILING

Postal Service with sufficient postage as First Class Mail in an envelope addressed to:

Assistant Commissioner for Patents, Washington, D.C. 20231

Docket No. 99-34R1

RECEIVED TC 1700

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Group Art Unit: -

Examiner: Unknown

In re Application of:

Washington, D.C. 20231

8114/02

Hagemeyer et al.

Serial No.:

09/901.85

Filed:

For:

Methods for Analysis of Heterogeneous Catalysts in a Multi-Variable Screening

Assistant Commissioner for Patents

INFORMATION DISCLOSURE STATEMENT

Sir:

Applicants submit herewith patents, publications and other information of which they are aware, which they believe an examiner may consider to be material to the patentability of the claims of this application, and in respect of which there may be a duty to disclose in accordance with 37 C.F.R. § 1.56.

While this Information Disclosure Statement may contain "material" information pursuant to 37 C.F.R. § 1.56, it is not intended to constitute an admission that any patent, publication or other information referred to herein is either "material" or "prior art" to the invention disclosed and claimed in the above-referenced application unless specifically designated as such. Applicants specifically reserve the right, where appropriate, to avoid or antedate any such reference by the appropriate arguments or showings under 37 C.F.R. § 1.131 and § 1.608, or any other appropriate means.

A completed PTO Form 1449 listing each reference is submitted herewith, and it is respectfully requested that an Examiner initialed copy of the PTO Form 1449 be returned to the undersigned. A copy of each reference therein listed accompanies this Information Disclosure Statement.

This Information Disclosure Statement is being filed within three months of the filing or entry of the national stage of this application, or before the mailing of a first Office Action on the merits, whichever is later. No fee is required under 37 C.F.R. § 1.97(b). However, in the event that more than 90 days from filing have elapsed and a first

In. mation Disclosure Statement Docket No. 99-34R1 Serial No.: 09/901,858

Page 2 of 2

Office Action on the merits has been mailed, the Commissioner is hereby authorized to charge the fee required under 37 C.F.R. 1.17(p) to Deposit Account Number 50-0496.

The Examiner is hereby requested to consider these references and other information and make them of record in the above-referenced application. Applicants respectfully submit that the claims of this application are patentable over the above-cited references and information. Examination and allowance of this application at an early date are requested.

Respectfully submitted,

Date: 14.19,000

Symyx Technologies, Inc. 3100 Central Expressway Santa Clara, CA 95051 Tel: (408) 773-4027 Fax: (408) 773-4029 Paul A. Stone, Registration No. 38,628



MATION DISCLOSURE **CITATION**

		US PATENT DOCUMENTS			
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME		

Tan.	Mt.		ATTORNEY'S DOCKET NO.:	APF	PLICATION NO.:	
MEN'S MATION DISCLOSURE CITATION		99-34R1	09/9	001,858 AU OUP:	900	
	PTO-1449		APPLICANT:		41	- C
			Hagemeyer et al.		办 "	G20.7
			FILING DATE: 7/9/2001	GR 176	OUP:	700°
		US PA	ATENT DOCUMENTS			
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	DATE
····	4,705,669	11/10/87	Tsuji et al.	422	93	8/27/86
	4,869,282	9/26/89	Sittler et al.	137	15	12/09/88
	5,776,359	7/07/98	Schultz et al	252	62.51	5/08/95
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EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANS YES	LATION NO
	DE 27 14 939 B2	11/29/79	Germany	G01N	31/10		×
,,, <u>,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,,</u>	DE 196 32 779 A1	2/19/98	Germany	G01N	35/00	×	
	DE 198 05 719 A1	8/19/99	Germany	B01J	35/04	×	
	DE 198 06 848 A1	8/19/99	Germany	B01J	35/02	×	
<u>- </u>	DE 198 09 477 A1	9/16/99	Germany	G01N	31/10	×	
	EP 0 796 654 A2	9/24/97	EPO	B01J	19/00		х

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THEORINATION DISCLOSURE CITATION

ATTORNEY'S DOCKET NO .:

APPLICATION NO.:

99-34R1

09/901.858

PTO-1449

APPLICANT:

Hagemeyer et al.

FILING DATE:

7/9/2001

GROUP: 1764

FOREIGN DOCUMENTS

EXAMINER'S INITIALS	PATENT NO.	DATE	COUNTRY	CLASS	SUB CLASS	TRANS YES	LATION NO
	WO 97/32208	9/04/97	PCT	G01N	31/10		x
	WO 98/03521	1/29/98	PCT	C07F	19/00		
	WO 98/07026	2/19/98	PCT	G01N	31/10	×	
	WO 98/13137	4/02/98	PCT	B01J	19/00		х
	WO 98/13605	4/02/98	PCT	F15C	5/00	<u> </u>	×
	WO 98/53236	11/26/98	PCT	F16K	31/126		х
	WO 99/41005	8/19/99	PCT	B01J	19/00	×	
	WO 00/09255	2/24/00	PCT	B01J	19/00		
	WO 00/14529	3/16/00	PCT	G01N	31/02		
	WO 00/17413	3/30/00	PCT	C23C	14/04		
	WO 00/51720	9/08/00	PCT	B01J	19/00		×
	WO 01/00315	1/04/01	PCT	B01J	19/00		×
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Control Applications"

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AUG 1 9 2002				
\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\\	ATTORNEY'S DOCKET NO.:	APPLICATION NO.:		
PADE CITATION	99-34R1	09/901,858		
PTO-1449	APPLICANT:	AL.		
	Hagemeyer et al.	GROUP:		
	FILING DATE: 7/9/2001	GROUP: 1764		
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EXAMINER:	DATÉ CONSIDER	RED:		

Examiner: Initial if reference considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



Docket No. 99-34R1
PATENT

1764

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service with sufficient postage as First Class Mail in an envelope addressed to: Assistant Commissioner for Patents, Washington, D.C. 20231 on 8114/02.

BY: Qui Day

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Hagemeyer et al.

Serial No.: 09/901,858 Group Art Unit: 1764

Filed: 7/9/01 Examiner: Unknown

Methods for Analysis of Heterogeneous Catalysts in a Multi-Variable Screening

Reactor

Assistant Commissioner for Patents Washington, D.C. 20231

TRANSMITTAL LETTER

Sir:

For:

RECEIVED AUG 2 0 2002 TC 1700

Transmitted herewith (check all that apply):

[] Preliminary Amendment	[X] Information Disclosure Statement
[] Response/Amendment	[] Petition Under 37 CFR 1.97(d)(2)
[] Response/Amendment After Final	[] Formal Drawings
[] Supplemental Amendment	[] Declaration Under 37 CFR 1.131
[] Affidavits/Declarations	[] Declaration Under 37 CFR 1.132
[] Declaration and Power of Attorney	[] Terminal Disclaimer
[] Supplemental Declaration	[] Small Entity Statement
[] Associate Power of Attorney	[] Request for Refund
[] Change of Correspondence Address	[] Appeal
[] Associate Power of Attorney	[] Petition
[] Request for Corrected Filing Receipt [] Sta	atus Letter

to be filed in the above-identified patent application.

[X] No fee is required.

[X] The Commissioner is hereby authorized to charge payment of any additional filing fees required under 37 C.F.R. § 1.16, in connection with the paper(s) transmitted herewith, or credit any overpayment of same, to Deposit Account No. 50-0496.

A duplicate copy of this Transmittal Letter is transmitted herewith.

Respectfully submitted,

Paul A. Stone

Reg. No. 38,628 Attorney for Applicant(s)

Date: Aug. 14, 2002

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